

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE
(Case No. 03-06)

In the application of:)	
)	
Harry Levinson and Thomas White)	
)	
Serial No.)	Examiner:
)	
Filed: January 12, 2004)	
)	Group Unit:
For: Method and System for Flattening a Reticle)	
within a Lithography System)	
)	

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Pursuant to 37 C.F.R. §§ 1.97 - 1.98, the Applicants wish to make the following documents of record in the above-identified application. This Information Disclosure Statement is in compliance with the duty of candor as set forth in 37 C.F.R. § 1.56. Copies of the documents cited below are enclosed. These documents are also listed on the enclosed PTO Form 1449.

In the judgment of the undersigned, portions of the listed documents may be material to the patentability of the presently pending claim. However, the documents have not been reviewed in sufficient detail to make any other representation and, in particular, no representation is intended as to the relative importance of any portion of the documents. This statement is not a representation that the listed documents have effective dates early enough to be "prior art" within the meaning of 35 U.S.C. § 102 or § 103.

Law Office of Monica H. Choi
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(614) 789-0241 (Fax)

List of Cited References

I. Patents

<u>Patent No.</u>	<u>Title</u>	<u>Inventors</u>
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II. Other

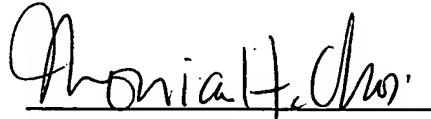
<u>Title</u>	<u>Publication Date</u>	<u>Relevant Pages</u>
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Method and System for Flattening a Reticle within a Lithography System		
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Respectfully Submitted,

Date: January 12, 2004

By:



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FORM PTO-1449 (Rev. 2-32)	U.S. Department of Commerce Patent and Trademark Office	Atty. Docket No. 03-06	Serial No.
		Applicant: Harry Levinson and Thomas White	
		Filing Date: January 12, 2004	Group:

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use several sheets if necessary)

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc).

			A. Mikkelsen et al., <i>EUVL Mask Flatness and Electrostatic Chucking Analysis</i> , Presented at the 47 th International Conference on Electron, Ion and Photon Beam Technology and Nanofabrication (Tampa, FL) and submitted to the Journal of Vacuum Science and Technology B, Nov/Dec, 2003

EXAMINER	DATE CONSIDERED
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication.